IMS 8f: AUTOMATED DYNAMIC SIMS FOR SEMICONDUCTOR AND ADVANCED MATERIALS CHARACTERIZATION

CAMECA
SCIENCE & METROLOGY SOLUTIONS
AMETEK

A new platform for advanced analytical challenges

Automated operation. Analytical versatility.
Proven magnetic sector SIMS performance.
From light elements and complex interfaces to shallow structures and deep profiles.



AUTOMATED ALIGNMENT

Less tuning. More understanding.

IMS 8f automates primary and secondary column alignment through a streamlined workflow, shortening time to measurement and delivering more consistent operating conditions. The result is better day-to-day reproducibility and more productive use of operator time, allowing greater focus on analytical insight rather than instrument setup.

- Shorter time to measurement
- Better day-to-day reproducibility
- More productive operator time

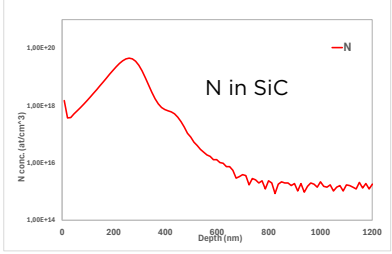
Automated Alignment
Primary- and secondary-column alignment

Expanded Analytical Foundation
New Cs source, PBMF architecture and improved vacuum design

Industrial Platform
New electronics and semiconductor deployment requirements

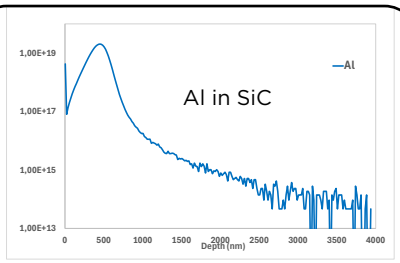
APPLICATIONS

From complex interfaces to deep distributions



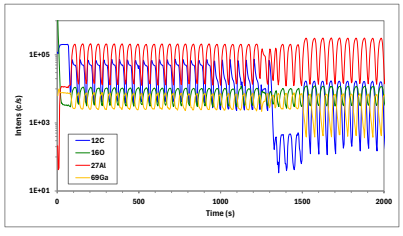
Light Elements in Semiconductors

Reveal critical light elements across advanced semiconductor materials.



Deep Dopant Profiling

Characterize dopant distributions through extended depth ranges.



VCSEL Depth Profiling

Resolve multilayer VCSEL structures with denser depth sampling.

DISCOVER IMS *8f*

A new Dynamic SIMS platform, engineered for advanced analytical challenges.